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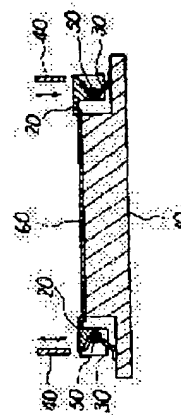
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(54) HOLDING EQUIPMENT FOR SUBSTRATE

(57)Abstract:

PURPOSE: To hold a substrate well on the surface of a substrate support board which has a simple construction and a free attitude by holding the substrate on the surface of the substrate support board fixing with a pawl pushed by a spring.

CONSTITUTION: A substrate holding equipment consists of a substrate support board 10, a pawl 20, a spring 30 and a pawl pusher 40. Around the surface of the substrate support board 10 where a substrate is placed, plural pawls 20 are provided in an appropriate interval. A spring attaching rod 50 is provided around the surface where the substrate is placed corresponding to the position of the pawl 20 and the spring 30 is provided placing one end against the support board 10. On the other end of the spring 30, the pawl 20 is provided and the pawl pusher 40 is provided corresponding to the opposite side end from the surface of the pawl 20. After a substrate 60 is placed on the surface, a mechanical chuck is moved to the original position and the outer circumference of the substrate 60 is kept in contact with the surface side end of the pawl 20 whereby the substrate 60 is pushed, fixed and held by the spring force of the spring 30 on the surface of the substrate support board.



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ABSTRACT:

PURPOSE: To hold a substrate well on the surface of a substrate support board which has a simple construction and a free attitude by holding the substrate on the surface of the substrate support board fixing with a pawl pushed by a spring.

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